

FORM PTO-1449			Docket Number (Optional) 008565-D7213		Application Number 09/218,997	
INFORMATION DISCLOSURE CITATION IN AN APPLICATION			Applicant <div style="text-align: right;">FUKAMI, Teruaki</div>			
(Use several sheets if necessary)			Filing Date December 22, 1998		Group Art Unit 1744	
U.S. PATENT DOCUMENTS						
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
cl	4,973,563	11/27/90	Prigge, et al.	—	—	
				—	—	
FOREIGN PATENT DOCUMENTS						
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION (YES/NO)
	0 702 399	3/20/96	EP	—	—	
	0 665 582	8/2/95	EP	—	—	
	4-130100	5/1/92	JP	—	—	
	4-101418	4/2/92	JP	—	—	
	0 674 343	9/27/95	EP	—	—	
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)						
cl	Morinaga, et al. "A Model for the Electrochemical Deposition and Removal of Metallic Impurities on Si Surfaces," IEICE Trans. Electron., Vol. E79-C. No. 3, March 1996, pp. 343 – 362.					
cl	Ohmi, et al. "Metallic Impurities Segregation at the Interface Between Si Wafer and Liquid during Wet Cleaning," J. Electrochem. Soc., Vol. 139 (1992), No. 11, November 1992, pp. 3317 – 3335.					
EXAMINER <i>Edward L. Smith</i>		DATE CONSIDERED <i>9/27/00</i>				
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.						

300P 1700
 22/98

